

Title (en)

SYSTEM AND METHOD FOR MANUFACTURING THIN FILM ELECTRICAL DEVICES

Title (de)

SYSTEM UND VERFAHREN ZUR HERSTELLUNG VON ELEKTRISCHEN DÜNNFILMBAUELEMENTEN

Title (fr)

SYSTÈME ET PROCÉDÉ DE FABRICATION DE DISPOSITIFS ÉLECTRIQUES À COUCHE MINCE

Publication

EP 2308082 A1 20110413 (EN)

Application

EP 08794858 A 20080730

Priority

US 2008009182 W 20080730

Abstract (en)

[origin: WO2010014058A1] A system for manufacturing a thin film electrical device is provided in accordance with an exemplary embodiment. The system includes a chamber and a gas gate. The chamber includes accumulating apparatus therein configured for gathering a portion of the substrate within the chamber. The gas gate provides fluid communication between a pressure region of the chamber and a second pressure region.

IPC 8 full level

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CPC (source: EP)

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Citation (search report)

See references of WO 2010014058A1

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